

Features

- Double Poly / Double Metal
- 4 μm Poly and Metal I Pitch
- 320 ps Delay per stage (Ring Osc.)
- 5.5 Volts Maximum Operating Voltage
- 2.7~3.6 Volts Low Voltage Option
- Shrinkable to Mitel 1.5 μm Process
- Low TCR Resistor Module
- ProToDuction[™] Option for fast prototypes
- Standard Cells Library

Description

The 2 μm P-Well process provides flexibility, speed and packing density needed in mixed signal designs. The aggressive design rules make it comparable to most 1.5 μm processes. Also, the MOSFET transistors are designed with very shallow source-drain junctions and a thin gate oxide to improve speed. A low voltage option is available for 3 volts applications. It offers low and matched threshold voltages for improved dynamic range needed in mixed analog/digital applications. A process module can be integrated to provide high precision and very low TCR polysilicon resistors.

Process Parameters

Process Parameters	2 μm 5volts & 3volts	Units
Metal I pitch (width/space)	2 / 2	μm
Metal II pitch (width/space)	2.6 / 2.4	μm
Poly pitch (width/space)	2 / 2	μm
Contact	2 x 2	μm
Via	2.4 x 2.4	μm
Gate geometry	2	μm
P-well junction depth	4	μm
N+ junction depth	0.20	μm
P+ junction depth	0.28	μm
Gate oxide thickness	325	Å
Inter poly oxide thick.	500	Å

MOSFET Electrical Parameters

Electrical Parameters	2 MICRON - 5 volts			2 MICRON - 3 volts			Units	Conditions						
	N Channel min.	typ.	max.	P Channel min.	typ.	max.			N Channel min.	typ.	max.	P Channel min.	typ.	max.
Vt (10x2 μm)	0.55	0.70	0.85	0.55	0.70	0.85	0.35	0.50	0.65	0.35	0.50	0.65	V	saturation
I _{ds} (10x2 μm)	160			70			175			80			$\mu\text{A}/\mu\text{m}$	V _{ds} =V _{gs} =5volts
Gain β (10x2 μm)	325			120			325			120			$\mu\text{A}/\text{V}^2$	
Body Factor (50x50 μm)	0.40			0.40			0.35			0.35			$\sqrt{\text{V}}$	
Bvdss	10	12		10	13		10	12		10	13		V	I _{ds} =100nA
Subthreshold Slope	100			100									mV/dec.	V _{ds} =0.1v
Substrate Current	0.25		0.34				0.25		0.34				$\mu\text{A}/\mu\text{m}$	V _{ds} =5.5v; V _{gs} =2.7v
Field Threshold	10	18		10	17		10	18		10	17		V	I _{ds} = 14 μA
L Effective	1.8			1.7			1.8			1.7			μm	L drawn = 2 μm

2 Micron CMOS Process Family

Capacitances (fF/ μm^2)

	2 μm 5 volts & 3 volts		
	min.	typ.	max.
Inter-poly	0.62	0.73	0.84
Gate oxide	.99	1.06	1.15
N+ Junction	.195		
P+ Junction	.138		

Bipolar gain¹

	2 μm - 5 volts		
	min.	typ.	max.
NPN vertical	300		

¹Test condition : Vce = 5 volts

Resistances ($\Omega/\text{sq.}$)

	2 μm 5 volts & 3 volts			Temp. coef. ($\Omega/\text{sq.}$) $^{\circ}\text{C}$
	min.	typ.	max.	
Pwell	13000			140
Pfield in Pwell	3000	3600	4200	32
N+	35	45	55	.06
P+	80	100	120	.15
Poly gate	15	20	25	.02
Poly capacitor	75	100	125	.06
Metal I	0.038			
Metal II	0.038			

FIG 1: I-V Characteristics for a 50x2 μm N-MOSFET (2 μm 5 volts process)

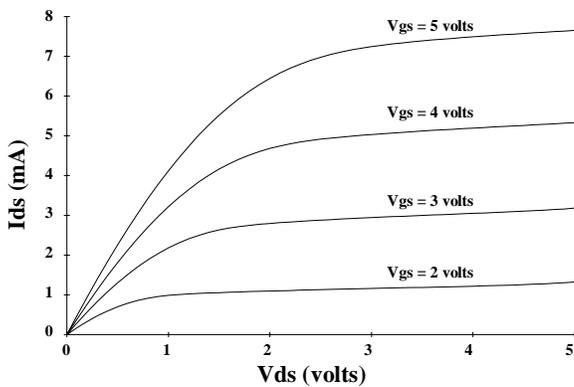


FIG 2: I-V Characteristics for a 50x2 μm P-MOSFET (2 μm 5 volts process)

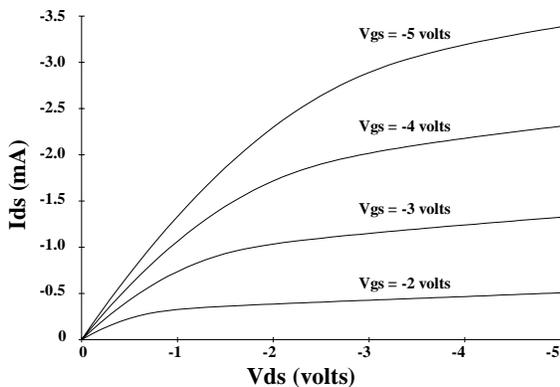


FIG 3: Subthreshold Characteristics at Vds=0.1 volts for a 50x2 μm N-MOSFET (2 μm 5 volts Process)

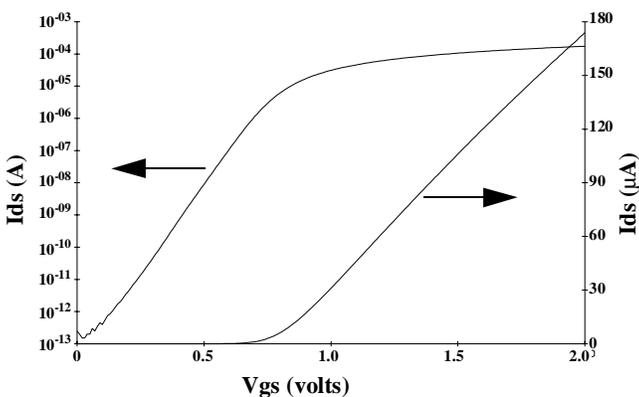
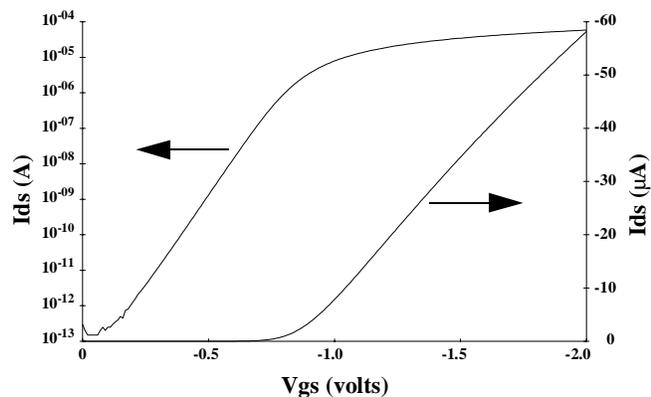


FIG 4: Subthreshold Characteristics at Vds=-0.1 volts for a 50x2 μm P-MOSFET (2 μm 5 volts Process)



Note: These values are for guidance only. Many of them can be adjusted to suit customer requirements. For full process specifications contact a Mitel sales office or representative.